Plasmonics: Design, Materials, Fabrication, Characterization, and Applications XXII

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Contents

v Conference Committee

PLASMONIC MATERIALS AND NANOSTRUCTURES I

13111 02 Tunable electro-optic resonant metasurfaces (Invited Paper) [13111-14]

PLASMONIC APPLICATIONS I

13111 03 Metasurface perfect absorbers for light control: beyond visible and infrared emitters (Invited Paper) [13111-23]

FUNDAMENTAL OF PLASMONICS II

13111 04 Emission modification of Sm³⁺ doped glass due to plasmon effect [13111-17]

METASURFACES IV

13111 05 Metasurface-based depth sensing and topology optimized high-Q metasurfaces (Invited Paper) [13111-33]

PLASMONIC MATERIALS AND NANOSTRUCTURES III

13111 06 Plasmonic nano-disks arrays made with electron beam lithography using the dots-on-the-fly method [13111-49]

METASURFACES VI

13111 07 An unconventional take on plasmonic metasurfaces (Invited Paper) [13111-55]

PLASMONIC MATERIALS AND NANOSTRUCTURES V

- 13111 08 Self-organization via 3D printing of anisotropic plasmonic structures [13111-65]
- 13111 09 Plasmon effect provides emission stabilization of glass matrices under high temperature [13111-66]

POSTER S	ESSION
----------	--------

13111 OA	Methodology for robust process window discovery in plasmonic nanostructures [13111-72]
13111 OB	High-efficiency plasmonic filter-based microlens array for multispectral infrared sensor [13111-74]

13111 OC Effects of defocusing on near-field intensity enhancement [13111-76]